First results on the charge collection efficiency of heavily irradiated microstrip sensors fabricated on oxygenated p-type silicon.

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OUTLINE:

- •Oxygen enrichment of n-type and p-type substrates
- •Production and irradiation of miniature detectors
- •First results of irradiated miniature detectors made on p-type oxygenated wafers



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2 sets of variously flavoured detectors have been produced by CNM using a Liverpool designed maskset. Four type of substrate were used: n-type with and without O, p-type with and without O. [O] calculated to be $\geq 10^{17}$ cm⁻³ throughout the wafer.

The 2 sets have been irradiated to 2.7 and 11.5 10¹⁴ p cm⁻² in the CERN-PS, Irrad-1 facility, at room temperature and unbiased.

After irradiation they were kept at low temperature.



Before irradiation: n-in-p detectors

 $V_{fd} \sim 350 \text{ V}$



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Reverse currents after 1.1 10^{15} 24 GeV/c p cm⁻²





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Charge collection has been measured using a 1060 nm laser and a β ¹⁰⁶Ru source. Good agreement of results.



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P-in-n with oxygenated substrate at the two different doses.





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Charge collection with n-in-p detectors after $2.7 \ 10^{14} \text{ p cm}^{-2}$. The presence of oxygen has small influence on the full depletion voltage.





Charge collection with n-in-p detectors after 1.1 10^{15} p cm⁻². Again, the presence of oxygen has small influence on the full depletion voltage.





N-in-p with oxygenated substrate at the two different doses. The full depletion voltage does not vary much.





V_{fd} vs proton fluence





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Charge deficit vs proton fluence





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CONCLUSIONS

- Oxygenated p-type substrate has been successfully used to produce miniature micro-strip detectors
- The p-type substrates show CCE properties at least as good as n-type substrates

⇒ since n-in-n micro-strip detectors show significantly lower voltages required for a given CCE, n-in-p should offer the same advantage but without the need for double-sided processing

• The oxygenated p-type detectors show less dependence of the full depletion voltage on dose.

⇒ this may be due to the lower resistivity starting material and/or due to the non-inversion of the substrate

• Further studies with initial higher resistivity of the p-type substrate are needed to qualify this substrate as a detector material.

